

Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) Substrate treatment equipment comprising:
 - a substrate treatment chamber,
 - a substrate holder that can be inserted into the substrate treatment chamber and holds substrates in a multistage manner in a substantially vertical direction,
 - a sensing device for sensing a holding condition of the substrates held in the substrate holder,
 - a substrate transfer unit that automatically leaves a substrate, without requiring a user substrate transfer, that was determined to be in an abnormal substrate holding condition in the substrate holder and transfers from the substrate holder substrates other than a substrate which was determined to be in an abnormal substrate holding condition according to a result of the sensing the holding condition of the substrates using the sensing device,
 - a control device for controlling the substrate transfer unit.
2. (Currently Amended) The substrate treatment equipment according to claim 1, wherein the substrate transfer unit leaves the substrate determined to be abnormal and at least one of the substrates held on and under the substrate determined to be abnormal in the substrate holder and transfers the substrates other than the substrate determined to be abnormal and at least one of substrates held on and under the substrate determined to be abnormal from the substrate holder.
- 3 - 4. (Canceled)
5. (Previously Presented) The substrate treatment equipment according to claim 1, wherein the substrate transfer unit carries one at a time the substrates other than the substrate that was determined to be in the abnormal substrate holding condition.

6. (Previously Presented) The substrate treatment equipment according to claim 2, wherein the substrate transfer unit carries one at a time the substrates other than the substrate that was determined to be in the abnormal substrate holding condition and at least one of substrates held on and under the substrate determined to be abnormal.

7. (Previously Presented) The substrate treatment equipment according to claim 1, wherein the substrate transfer unit that senses the holding condition of the substrates using the sensing device, and when all of a predetermined number of substrates to be carried are determined to be in a normal substrate holding condition, carries together all the predetermined number of substrates, and when at least one of a substrate in the predetermined number of substrates is determined to be in the abnormal substrate holding condition, carries one at a time the substrates other than the substrate that was determined to be in the abnormal substrate holding condition in the predetermined number of substrates.

8. (Previously Presented) The substrate treatment equipment according to claim 2, wherein the substrate transfer unit that senses the holding condition of the substrates using the sensing device, and when all of a predetermined number of substrates to be carried are determined to be in a normal substrate holding condition, carries together all the predetermined number of substrates, and when at least one of a substrate in the predetermined number of substrates is determined to be in the abnormal substrate holding condition, carries one at a time the substrates other than the substrate that was determined to be in the abnormal substrate holding condition and at least one of substrates held on and under the substrate determined to be abnormal in the predetermined number of substrates.